AMENDMENT

IN THE CLAIMS:

Please amend the claims as follows:

1. (Currently Amended) A method of manufacturing a crystal resonator using a crystal substrate, comprising the steps of:

forming a crystal resonator area and a side electrode shielding/formation ~~blocks thereabout~~ block on said crystal substrate through etching by leaving a partial connection section, ~~and with~~ both ~~areas kept separate~~ said crystal resonator area and said side electrode shielding/formation block being separated from each other ~~with~~ by a gap; and

applying vapor deposition through said gap diagonally toward ~~the~~ a side of said crystal substrate, ~~producing an area where~~ whereby a film is formed on said side ~~and an~~ in a first area ~~where~~ but film formation is prevented in a second area of said side due to ~~by~~ the existence of ~~the~~ said side electrode shielding/formation ~~blocks~~ block, and thereby forming an electrode film bisected in the thickness direction of ~~the~~ said substrate on ~~the~~ said side.

2. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1, wherein by adjusting the size of ~~the~~ said gap between said crystal resonator area and ~~the~~ said side electrode shielding/formation block, said side electrode shielding/formation block is constructed ~~of~~ in an area where said bisected electrode film is formed and an area where formation of the said electrode film is prevented.

3. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1, wherein vapor deposition toward ~~the~~ said side of said crystal substrate is performed in a range of angle of incidence of ±45° to 55° with respect to ~~the~~ said side ~~of the crystal substrate~~.

4. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1, wherein said electrode film is divided into upper and lower portions and is formed on ~~the side of the~~ a vibration section of ~~the~~ said crystal resonator.

5. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 4, wherein $0.15t \leq d \leq 0.25t$ is held where t is the thickness of said vibration section and d is the distance between ~~the~~ two ~~divided~~ bisected electrodes on ~~the~~ said side ~~of the~~ , said side being on a tine for detection of Coriolis force.

6. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1,

wherein said crystal resonator is a quartz crystal tuning fork including a vibration section made up of a base and a plurality of vibration tines which extend from ~~the~~ said base, and

wherein said electrode film is divided into upper and lower portions ~~is formed~~ on ~~the~~ said side , said side being a side of ~~the~~ said vibration section and ~~the~~ a side of ~~the~~ said base.

7. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1,

wherein said crystal resonator is a resonator for a vibration gyro having three vibration tines, and

wherein said electrode film is divided into upper and lower portions ~~is provided~~ on ~~the~~ said side ~~of the~~ ,said side being on a tine for detection of Coriolis force out of said three vibration tines.

8. (Original) The method of manufacturing a small crystal resonator according to any one of claims 1 to 7, wherein the thickness t of said crystal resonator is $100\ \mu m \leq t \leq 350\ \mu m$.

9. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1,

wherein said crystal resonator is a quartz crystal tuning fork including a vibration section made up of a base and a plurality of vibration tines which extend from ~~the~~ said base, and

wherein part of said side electrode shielding/formation block is provided ~~so as to insert~~ between said vibration tines.

10. (Previously Presented) A small crystal resonator created using the manufacturing method according to any one of claims 1 to 7 and 9.

11. (Previously Presented) A small crystal resonator created using the manufacturing method according to claim 8.